

KX170 Series

Linton
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KX170 Semiconductor MCZ Crystal Growing Furnace



- **OPTIMIZED FOR 8" - 10" INGOT GROWTH**
(200 mm - 250 mm Ingot growth)
- **ADVANCED CONTROL SYSTEM**
- **LOW POWER CONSUMPTION**
- **INTEGRATED COMMUNICATIONS**
with optional WINGS systems

KX170MCZR



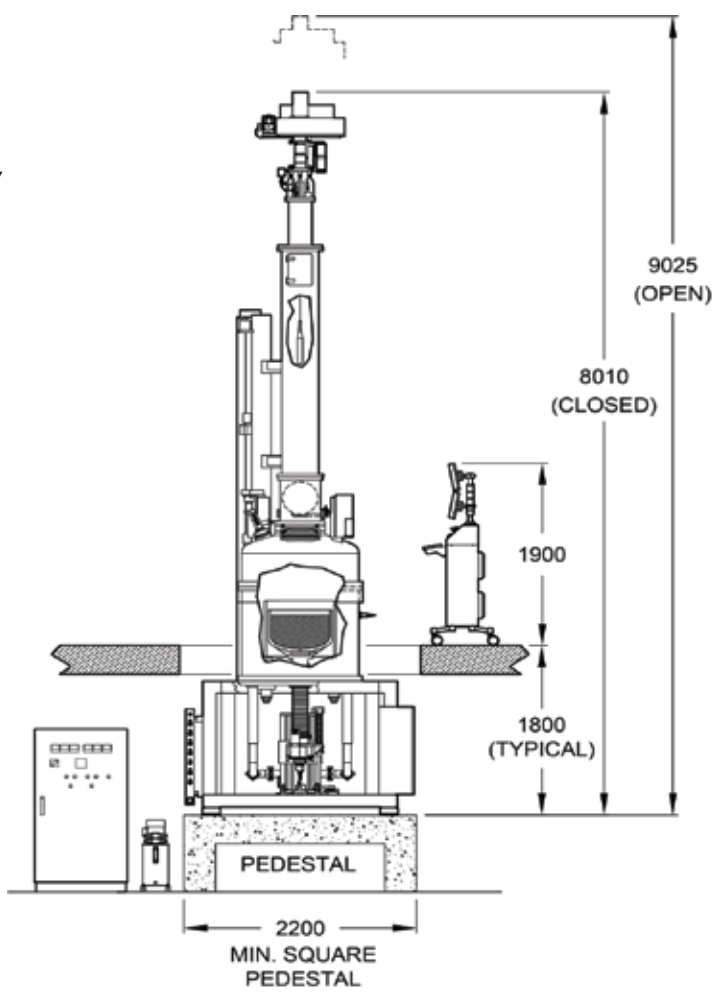
KX170

MCZ CRYSTAL GROWING FURNACE

The KX170 is the industry standard by which all others are judged. Since 2010 the 170 has been the workhorse of the semiconductor industry. The KX170 MCZR can accommodate up to a 24" hotzone. The KX170 MCZR is enabled for supporting a wide range of magnet options.

PERFORMANCE	
Furnace Chamber Diameter	1040 mm (40.9 in)
Receiving Chamber Height	2800 mm (110 in)
Throat Diameter	305 mm (12 in) Optional
Seed Lift Rate	0-508 mm/hr
Seed Jog Speed (Nominal)	400 mm/min
Seed Rotation (Reversible)	0-30 rpm
Total Crucible Travel	500 mm (19.6 in)
Crucible Lift Rate	0-127 mm/hr
Crucible Jog Speed (Nominal)	127 mm/min
Crucible Rotation (Reversible)	0-12 rpm
Dual Mass Flow Control	200 slpm (each)

SILICON CHARGE CAPACITY		
*Hot Zones available to fit following crucible size. Note: Charges enhanced with Xtramelt™ Feeder		
CRUCIBLE DIAMETER*	CRUCIBLE HEIGHT*	NOMINAL CHARGE SIZE
22.0 in	343 mm (13.5 in)	150 kg
24.0 in	483 mm (19.0 in)	200 kg



Dimensions shown are typical and can be customized to meet customer requirements

OPTIONS & ACCESSORIES	
Feeders	Vacuum Pumps
Hot Zones	Ingots and Crucible Handling
Filters	Maintenance Tools